



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Ko, *et al.* Attorney Docket: TSM02-1383
Filed: August 27, 2003 Examiner: TBD
Serial No.: 10/649,566 Art Unit: TBD
For: Method for Ultra Low-K Dielectric Deposition

Commissioner for Patents
P. O. Box 1450
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Respectfully submitted,


James C. Kesterson
Attorney for Applicant
Reg. No. 25,882

December 2, 2003

Date

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Respectfully submitted,


Julie Russell
Legal Assistant

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PTO/SB/08A (05-03)

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STATEMENT BY APPLICANT**

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of

2

Complete if Known

Application Number 10/649,566

Filing Date August 27, 2003

First Named Inventor Ko, *et al.*

Art Unit TBD

Examiner Name TBD

Attorney Docket Number TSM02-1383

U.S. PATENT DOCUMENTS

| Examiner Initials* | Cite No. ¹ | Document Number | Publication Date MM-DD-YYYY | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
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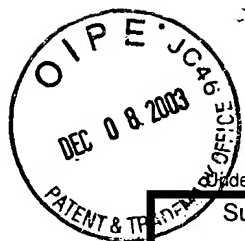
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| | A | SHAREEF, I.A., <i>et al.</i> , "Subatmospheric Chemical Vapor Deposition Ozone/TEOS Process for SiO ₂ Trench Filling", J. Vac. Sci. Technol. B 13(4), Jul/Aug 1995, pp. 1888-1892, 1995 American Vacuum Society. | |
| | B | NGUYEN S.V., "High-Density Plasma Chemical Vapor Deposition of Silicon-Based Dielectric Films for Integrated Circuits", IBM Journal of Research and Development, vol. 43, 1/2, 1999. | |
| | C | IBBOTSON, D.E., <i>et al.</i> , "Plasma Processing of Low K Dielectric Films", The Electrochemical Society, Inc., Washington, D.C., March 25, 2001. | |
| | D | BEEKMANN, K, <i>et al.</i> , "Low-k Dielectric Requirements and Zero-Overlay Compatibility", Semiconductor International October 21, 2001 | |
| | E | KALLENDER, P., "Toshiba, Fujitsu Report 100-Nanometer Process Gains", EE Times, November 8, 2001 | |
| | F | WALDFRIED, C, <i>et al.</i> , "Plasma Curing of Porous MSQ Films", 202 nd ECS Meeting, October 20-25, 2002. | |

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| Examiner Signature | | Date Considered | |
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| | G | LEE, H.J. <i>et al.</i> , "Structural Characterization of Porous Low-k SiOC Thin Films Using X-ray Porosimetry," publication and date unknown. | |
| | H | "MEMS Thin Film Deposition Processes," MEMS and Nanotechnology Clearinghouse, author and date unknown. | |
| | I | USAMI, K., <i>et al.</i> , "A Silica-Based Inter-Metal-Insulator with Low Dielectric-Constant and High Thermal Conductivity," publication and date unknown. | |
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